

# MicroForce™ Probing for Devices with Low-k ILD Materials

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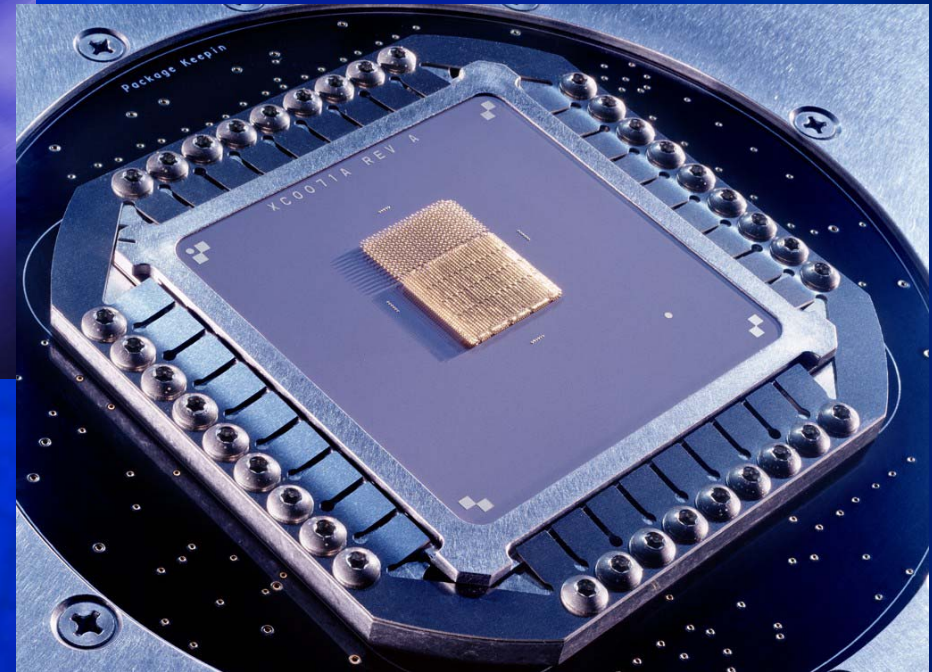
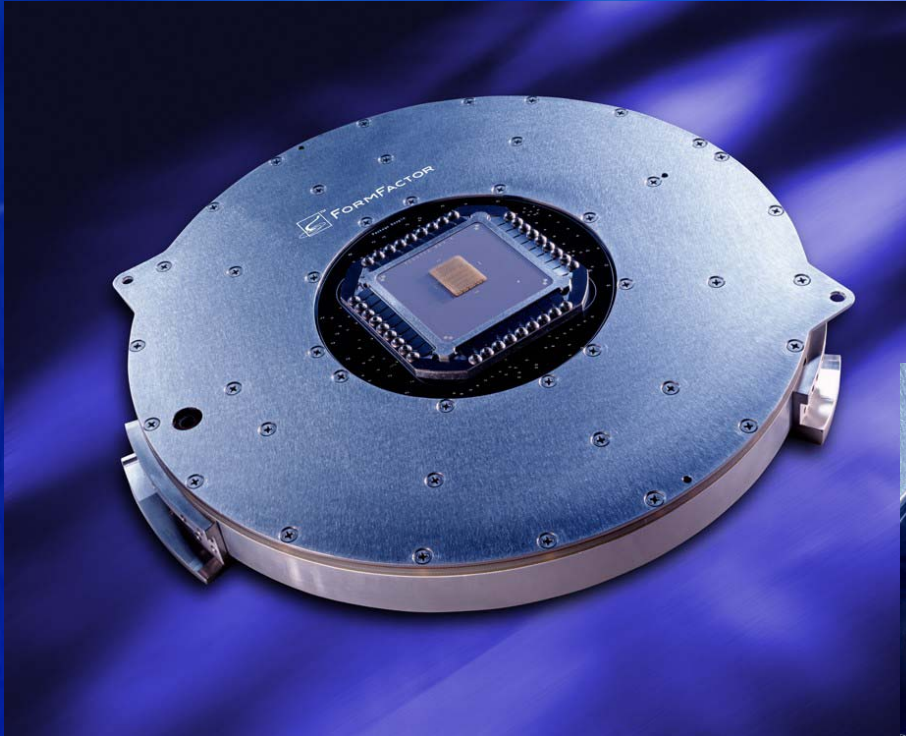
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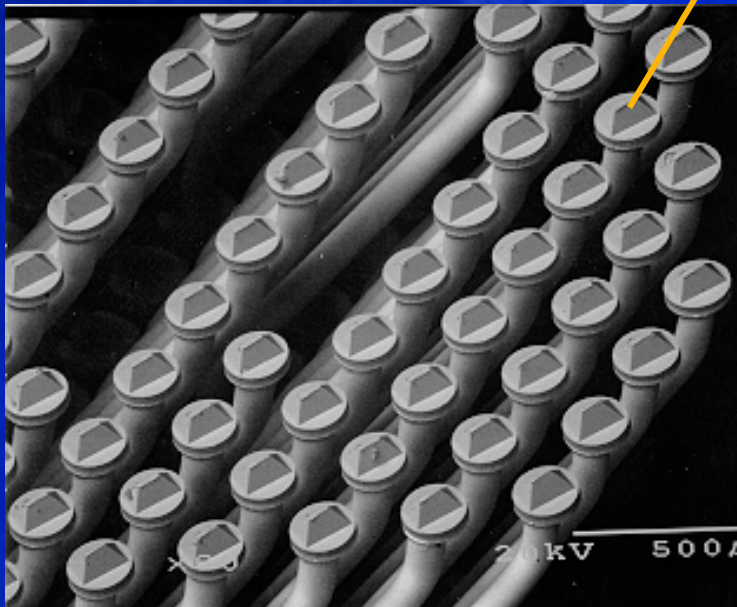
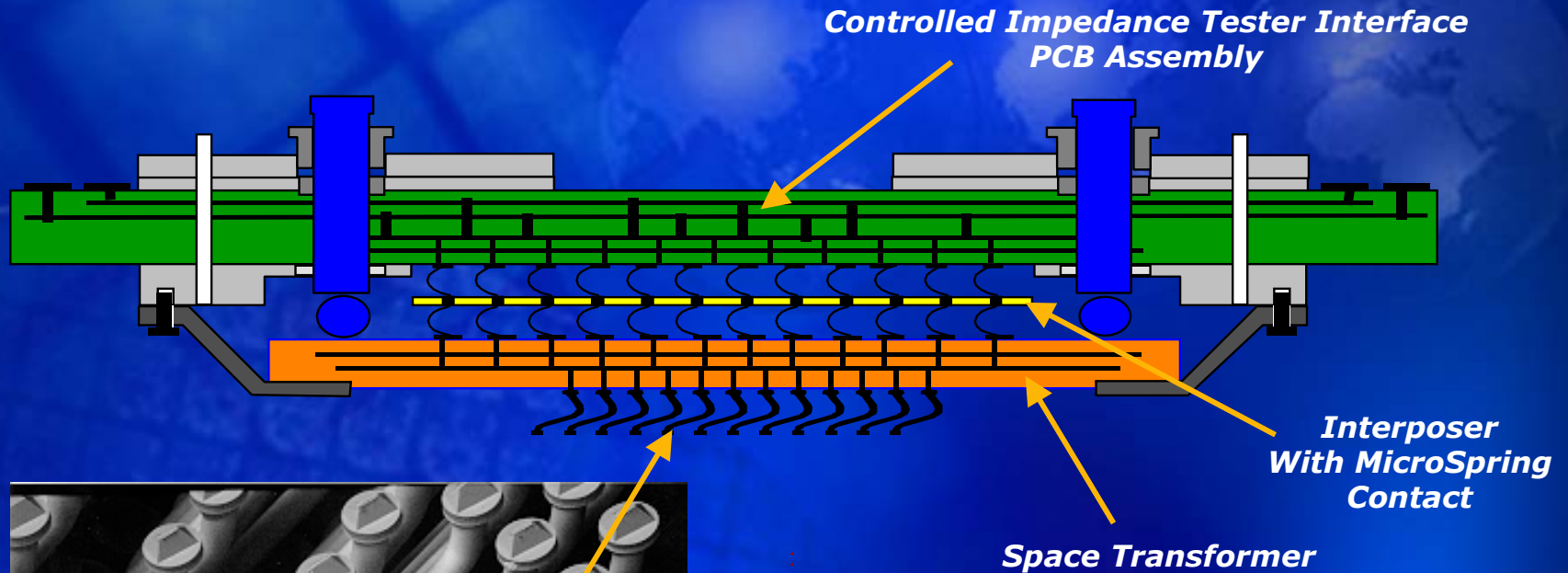
# Industry Requirements for Probing Advanced Flip Chip Bumped Devices

- Lower Force Probing
  - Low-k ILD materials are more fragile
  - Low probe force desired to minimize damage to flip chip bump and ILD materials
- Low and Consistent Contact Resistance
  - High frequency and high power applications require tighter Cres control
  - Applications require higher current to pass through probe system without much resistance
- Finer Pitch
  - Roadmap to 100 $\mu$ m pitch requires revolutionary probing approach

# FormFactor BladeRunner™ Probe Cards (For Probing Bumped Wafers)



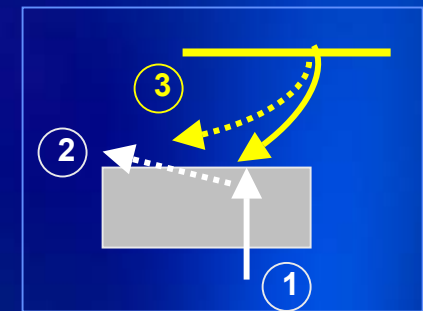
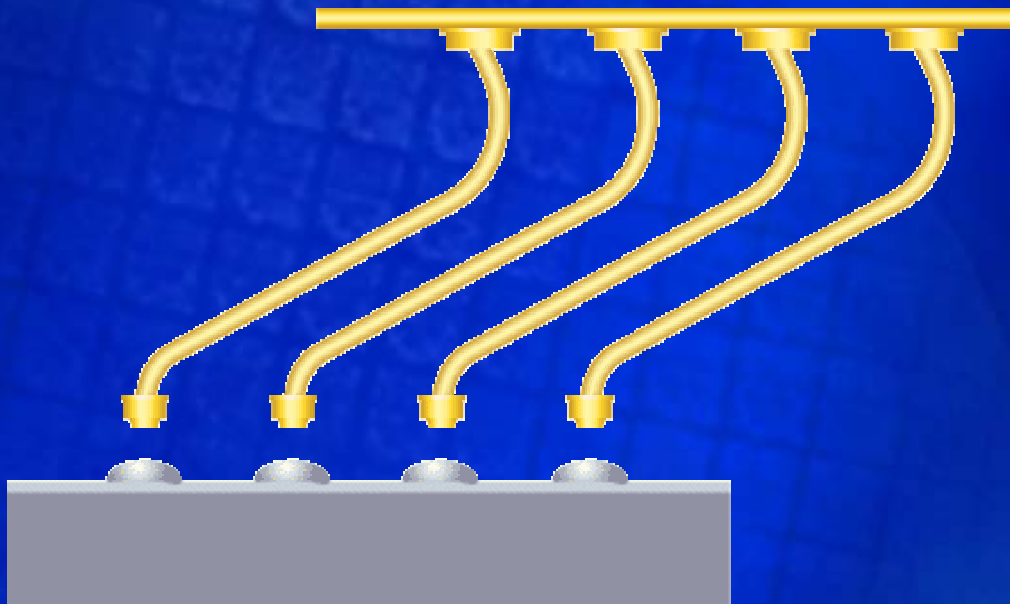
# FormFactor Probe Card Architecture



MicroSpring™ Contact for Probing Flip Chip Bumps

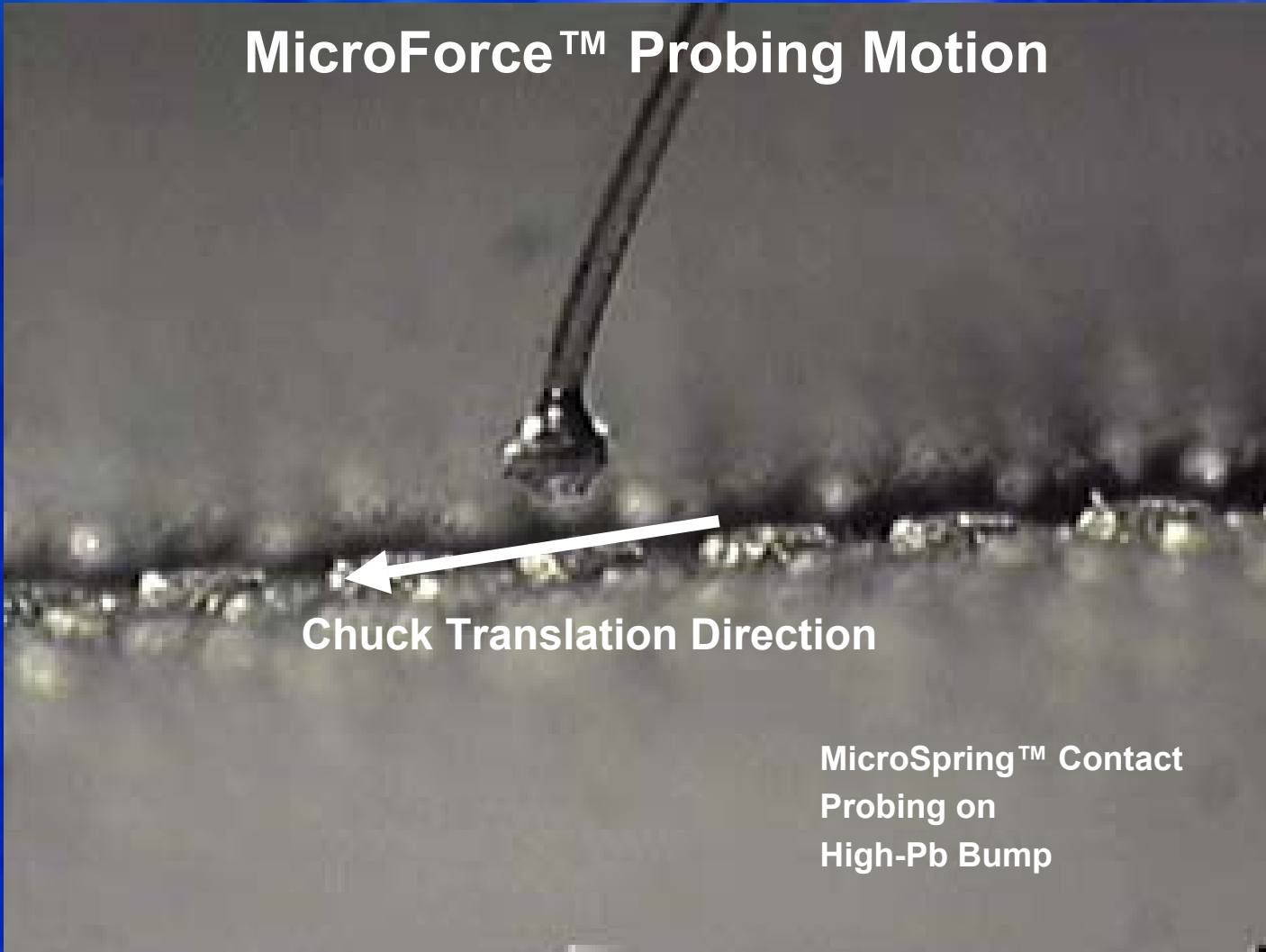
# MicroForce™ Probing Definition

- What is MicroForce™ probing?
  - It is a coordinated X-Y-Z probing motion
  - Developed to satisfy a number of stringent requirements for probing devices with low-k ILD materials
  - Breakthrough results with 10:1 reduction of probe force yet achieving consistent and low contact resistance



- 1 – Prober Chuck Moves in Z-axis
- 2 – Contact with Flip Chip Bump
- 3 – Chuck moves in X-Y-Z

# MicroForce™ Probing on Pb/Sn Bump



# FormFactor Laboratory Development

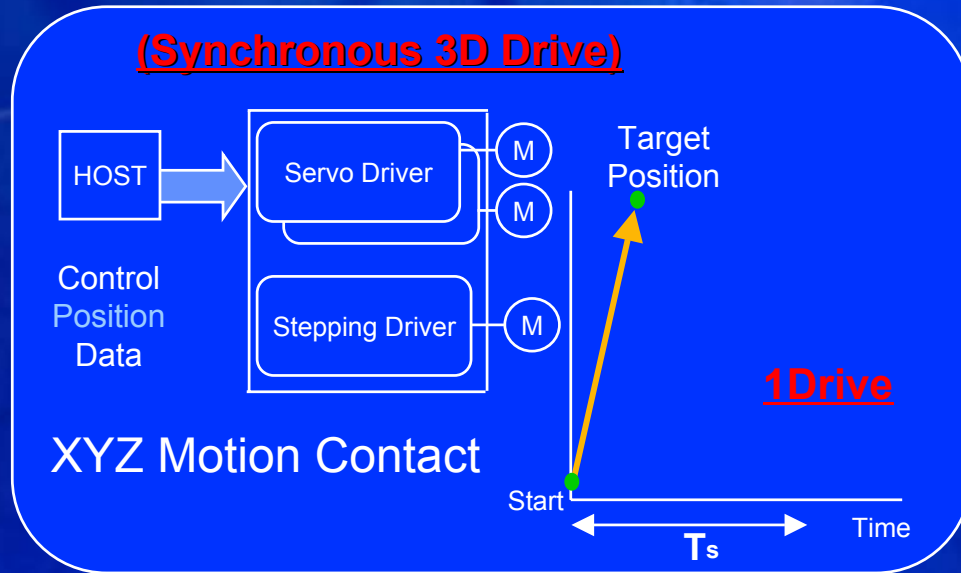




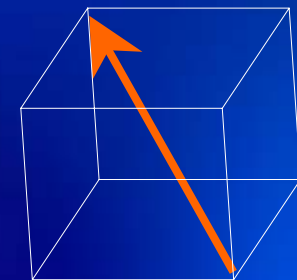
# TEL Synchronous XYZ Drive

## 3D drive control method

### (Synchronous 3D Drive)



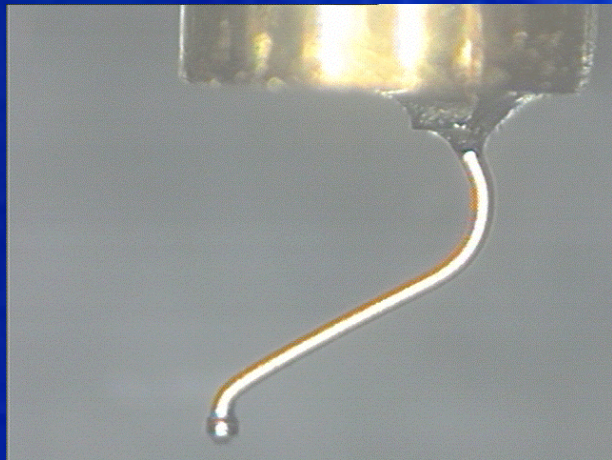
Simultaneous XYZ Drive



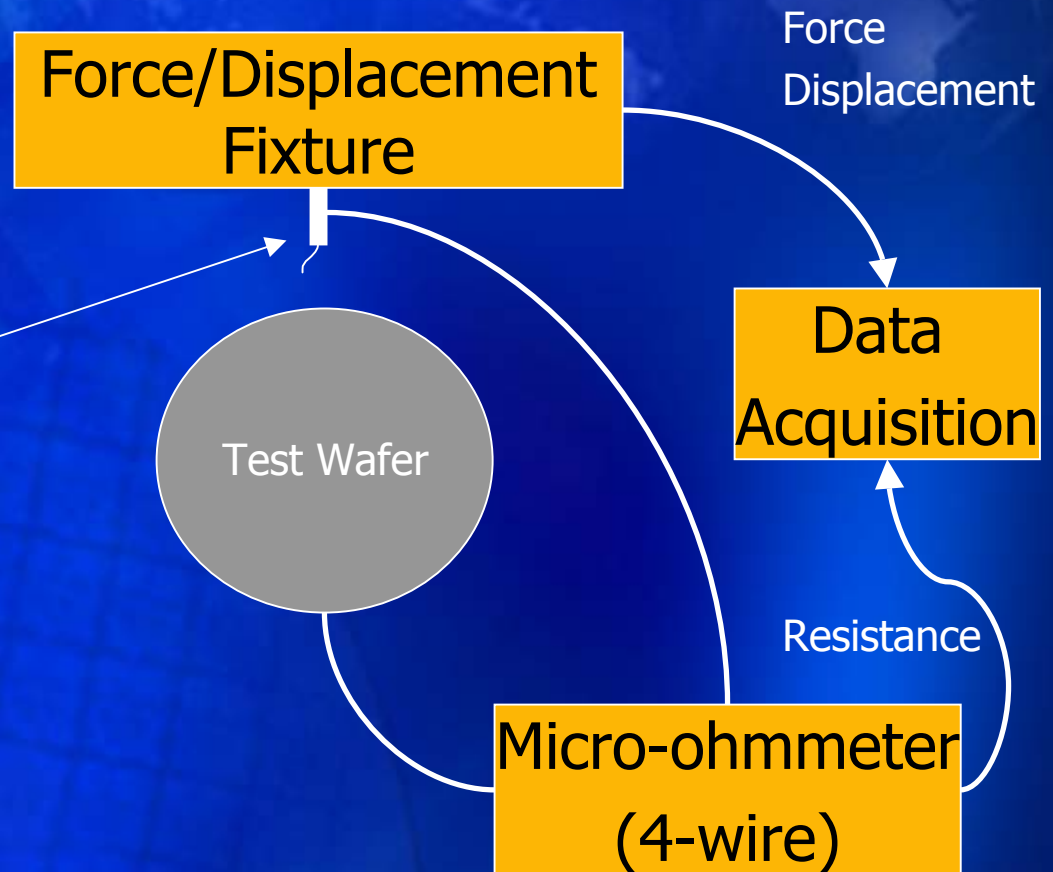
## Benefits

- Increased throughput with simultaneous XYZ drive
- Smooth drive creates desired probe contact

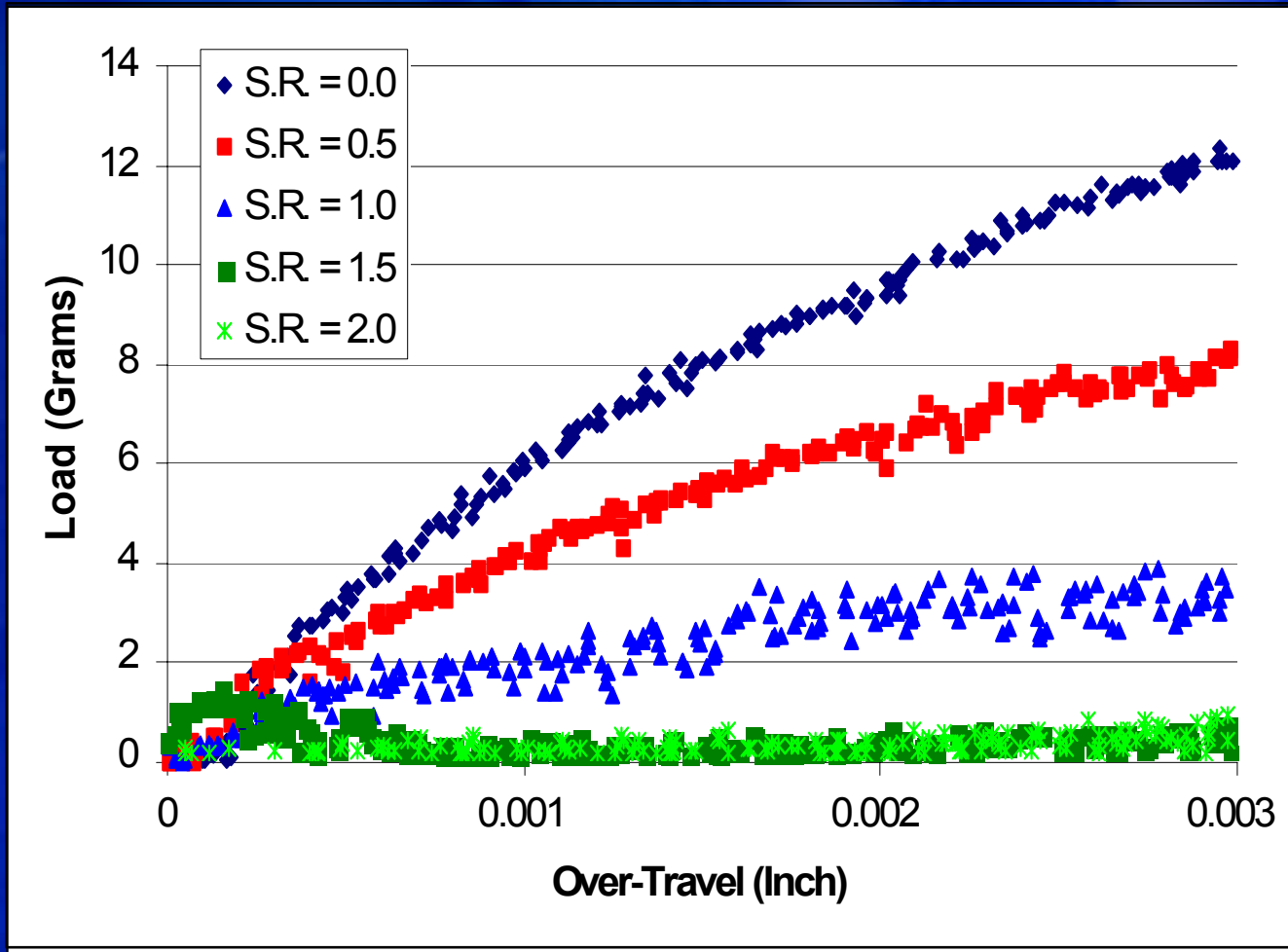
# Experimental Setup - Predictive Probing



Test Spring

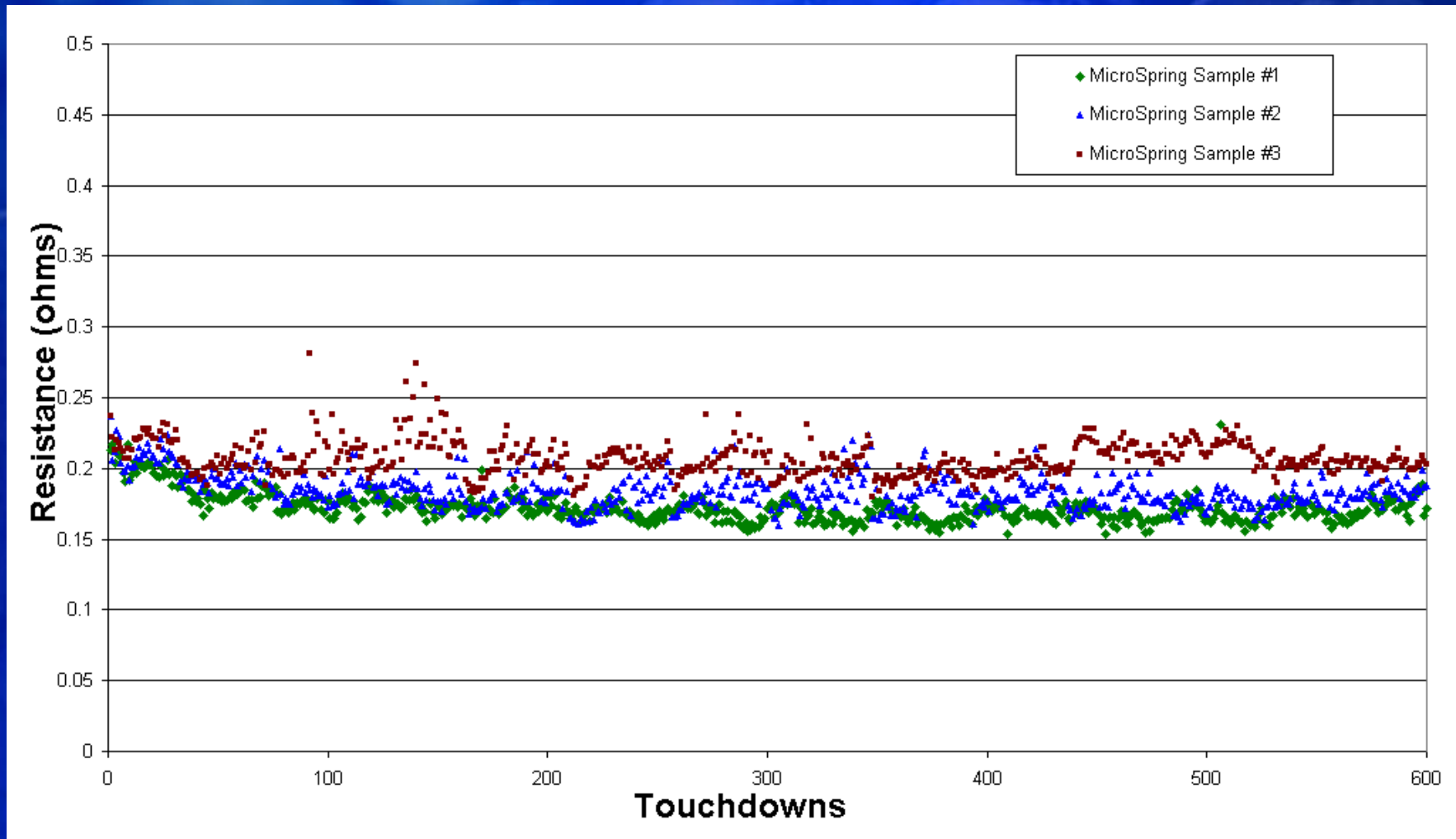


# Significantly Lowered Probe Force with MicroForce Feature



Scrub Ratio =  
 $\frac{\text{Movement in X/Y}}{\text{Movement in Z}}$

# Repeatability of Cres Study on Pb/Sn Bumps



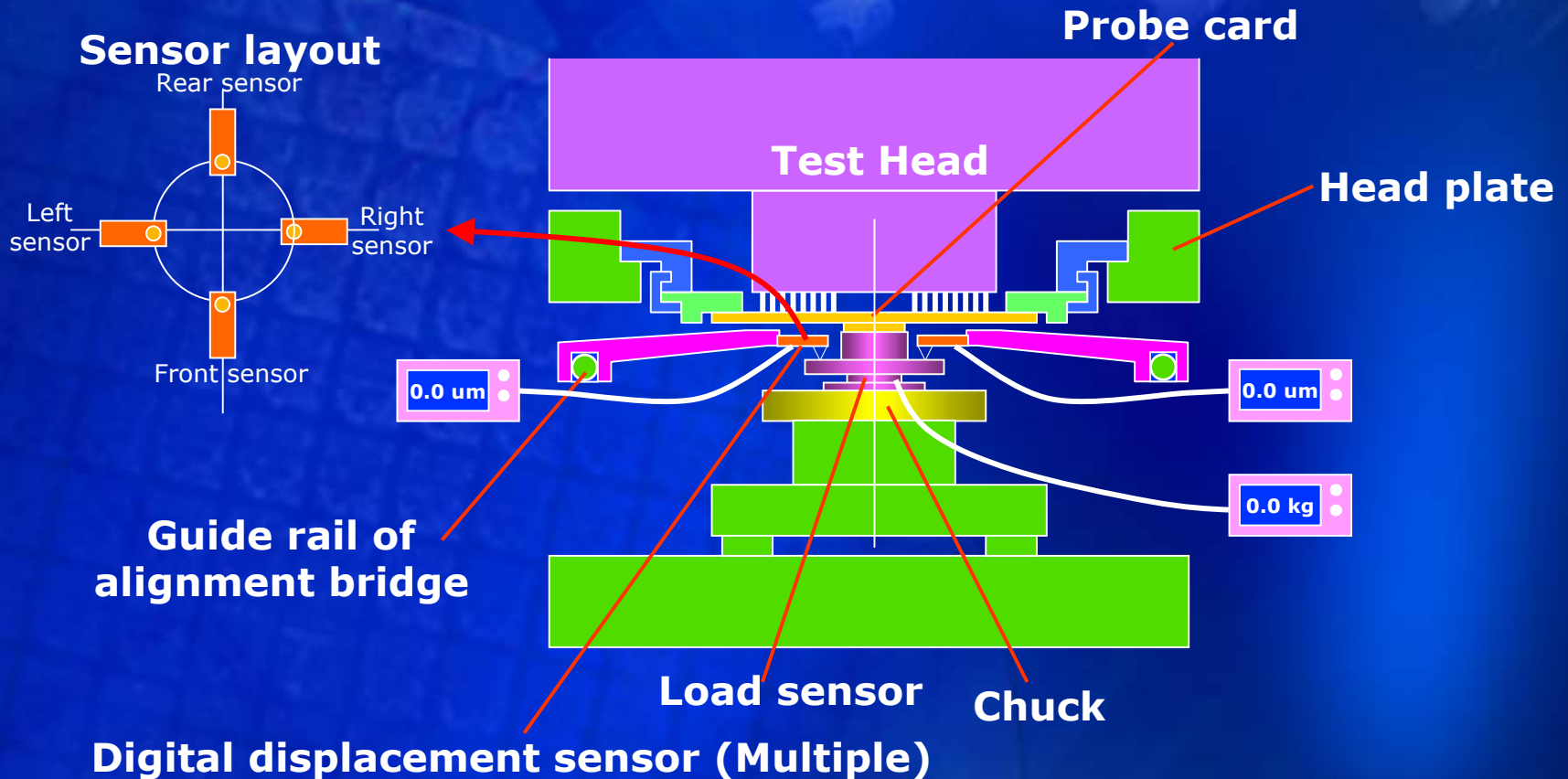
Stable and Low Contact Resistance with MicroForce Probing

# Sort Floor Validation

# Outline of Probe card Characteristics Measurement System

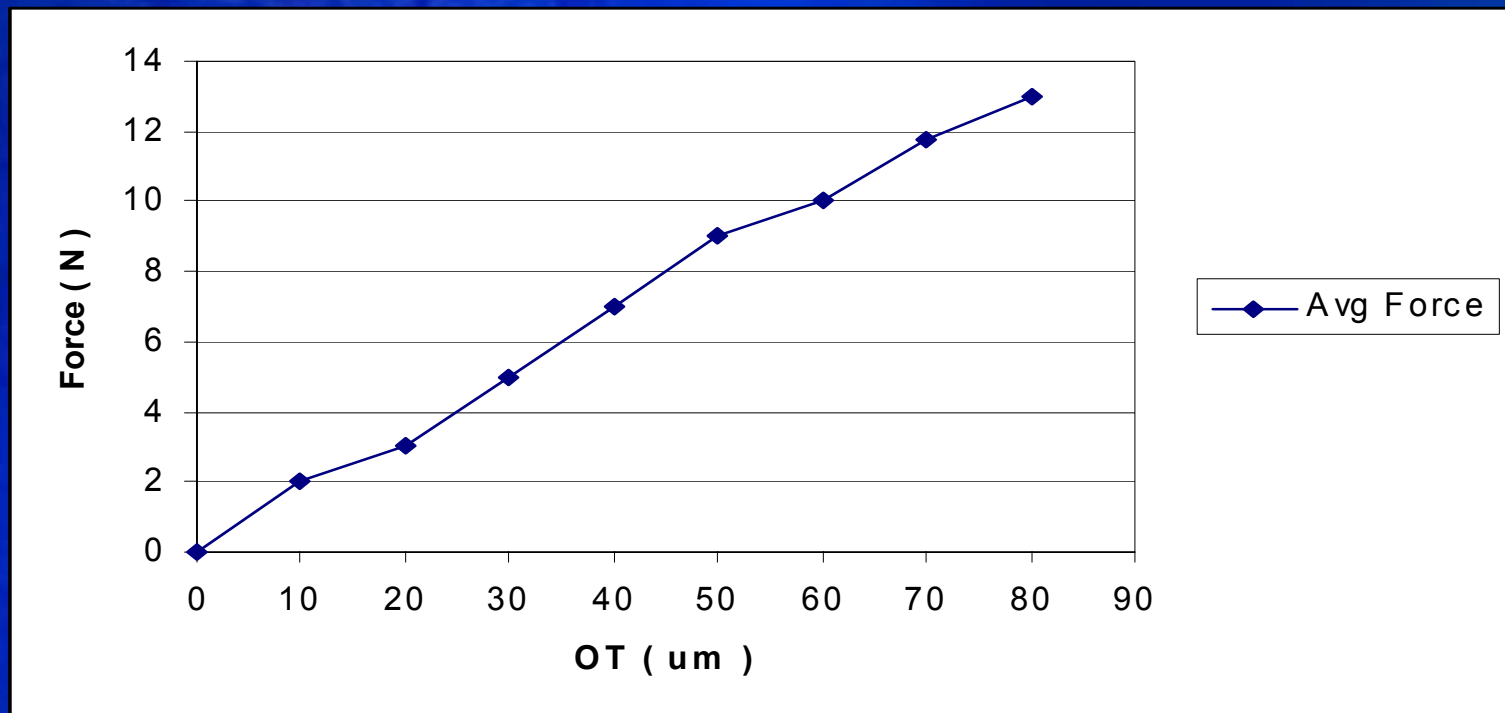
## Definition

PCMS is a measurement system that can measure the probe card displacement under load. The result of PCMS includes the displacement of head plate, probe card and probe card holder.



# Low Probing Force Using MicroForce Feature

- Used TEL's PCMS to evaluate probe card deflection under varying loads. Data generated included actual spring compression and probing force per dialed chuck motion.
- Max probing force = 13N at 80 $\mu$ m of spring over-travel
- Max force/probe = 0.3g/mil with MicroForce vs. 3 – 4g/mil without MicroForce



# Probing of Microprocessor Devices

- Testing

- Sort tests were run with and without MicroForce probing
- Correlation of device binning and other parametric indicators measured
- 3 production lots of microprocessor devices were tested

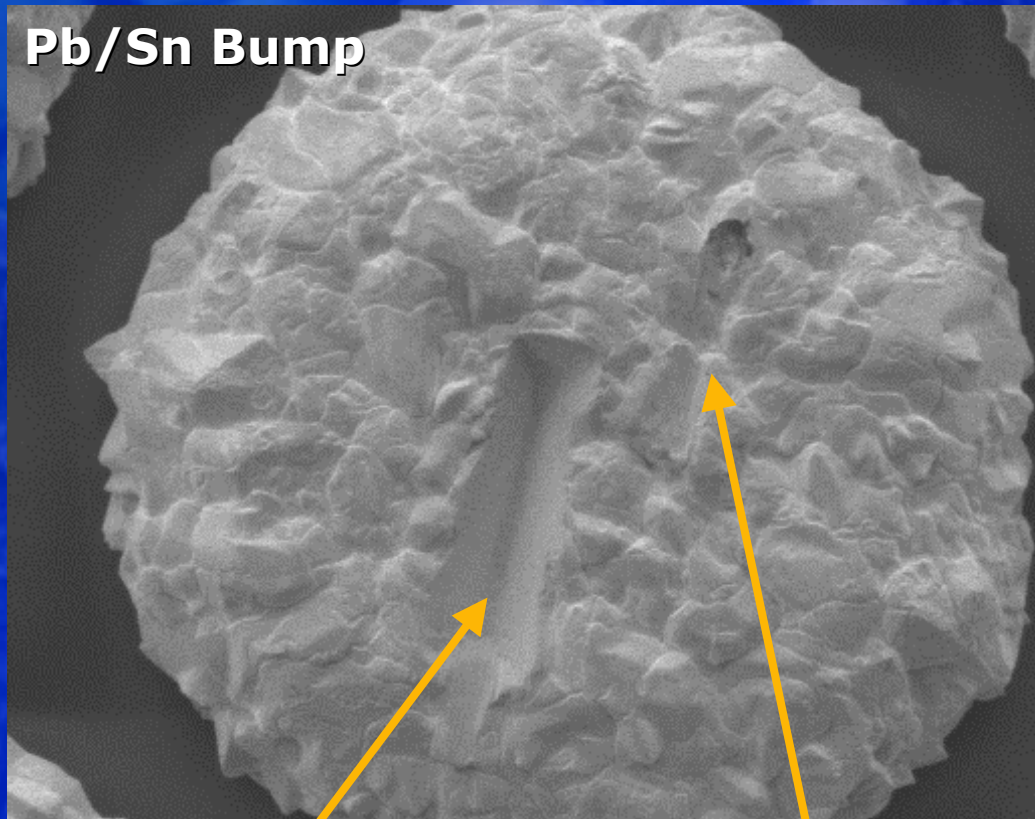
- Results

- Binning data collected under MicroForce had a correlation rate of 95.9 – 97.4% vs. existing probing Recipe (target is >95%)
- Other parametric measurements indicated comparable results
- No issues in terms of the mechanical and electrical behavior of the springs under MicroForce Probing. Metrology data remained within the defined specifications.





# Probe Mark Comparison



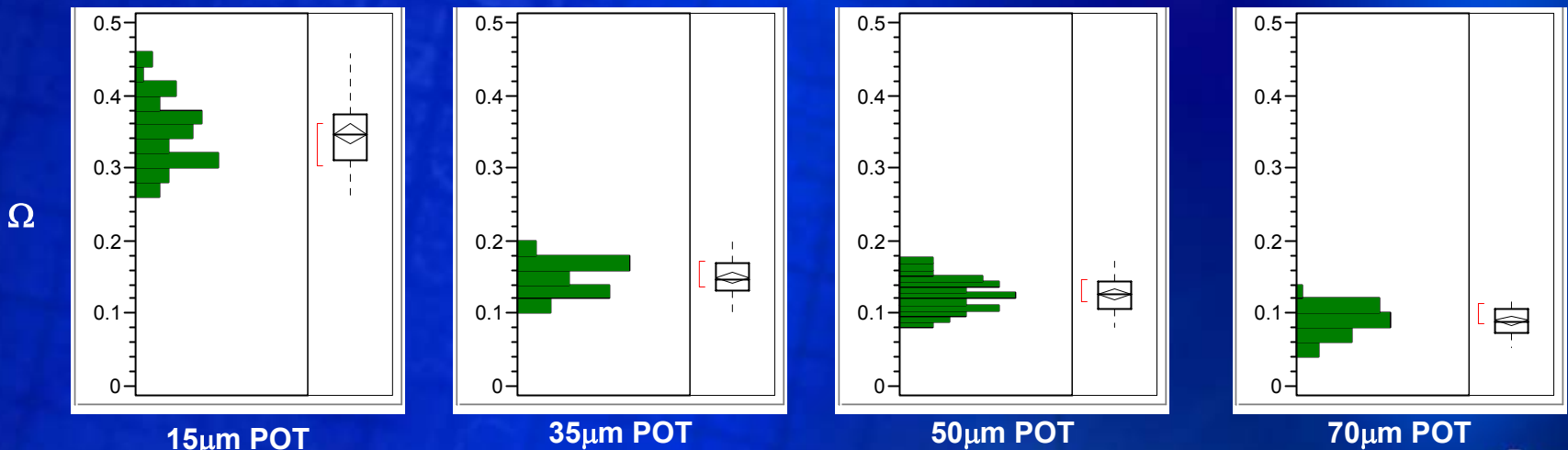
Standard Probing

MicroForce Probing

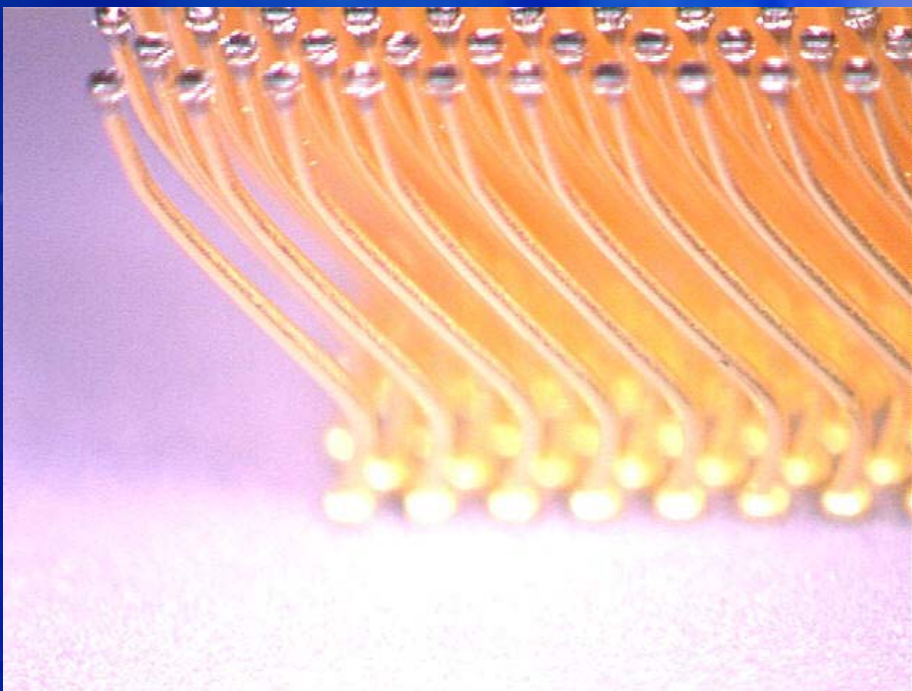
# Validation of MicroForce Low Cres

- Good convergence of Cres
- Mean Cres at different programmable overtravels: 0.1 – 0.35 $\Omega$
- Enabling a wide manufacturing process window

<u>POT um</u>	<u>Mean</u>	<u>Std Dev</u>
15	0.3466	0.047
35	0.1492	0.023
50	0.1256	0.024
70	0.0898	0.020



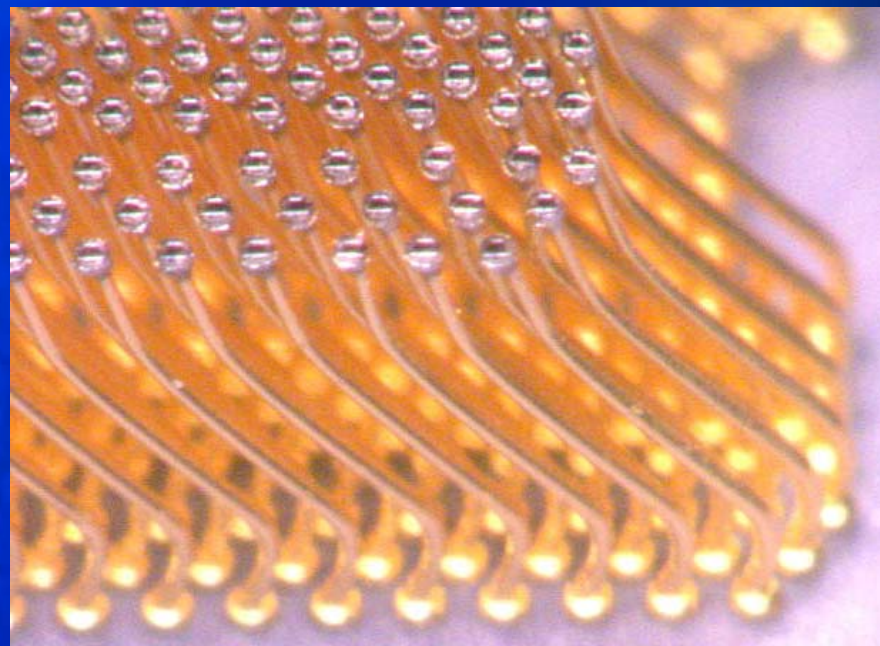
# MicroSpring Contact After Aging Test



New (after probing 6 wafers)

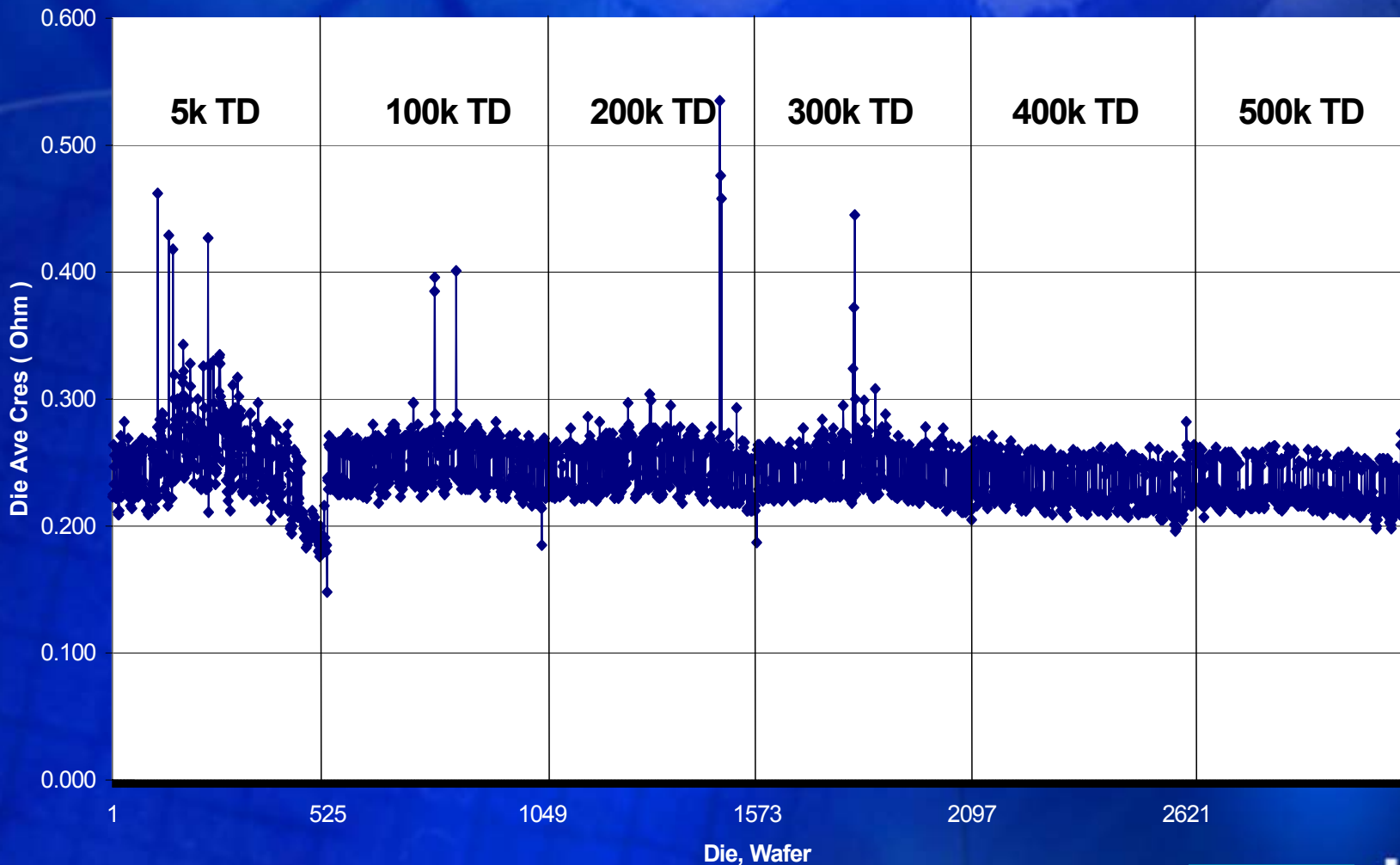


After 500,000 Touchdowns



# Cres Stability After Aging Test

Under MicroForce Probing, Cres remained stable for 500K touchdowns



# Conclusions

- **MicroForce Technology provided new capabilities to meet new-generation probing requirements.**
- **MicroForce Probing offered low contact resistance necessary for high power delivery requirements.**
- **MicroForce Probing delivered very low probing force (<2g) thus minimizing the risk to damage die with low-k ILD materials.**
- **Sort on production devices proved very stable and correlated to existing probing recipes. The solution satisfies Intel probing requirements.**
- **Future work will be targeted at:**
  - **Throughput Optimization**
  - **Production Sort Certification**

# Acknowledgment

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**FormFactor**

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**Intel**

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**TEL**

**Intel**

**FormFactor**

